Docket No.

263788US2PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

INVENTOR(S) Keisuke KAWAMURA, et al.

SERIAL NO:

10/519,475

ART UNIT: 1792

FILING DATE: December 28, 2004

EXAMINER: ARANCIBIA, M. G.

FOR:

PLASMA PROCESSING SYSTEM AND ITS SUBSTRATE PROCESSING PROCESS, PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION SYSTEM AND ITS FILM DEPOSITION PROCESS

FEE TRANSMITTAL

□ No additional f	fee is	required
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☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.

The Fee has been calculated as shown below:

FOR NUMBER FILED		NUMBER EXTRA	RATE	CALCULATIONS
TOTAL CLAIMS	8 - 20 =	0	x \$52 =	\$0.00
INDEPENDENT CLAIMS	6 - 4 =	2	x \$220 =	\$440.00
☐ MULTIPLE DEPENDEN	\$0.00			
☐ LATE FILING OF DECL	\$0.00			
	\$0.00			
	\$440.00			
☐ REDUCTION BY 50% F	\$0.00			
☐ FILING IN NON-ENGLI	\$0.00			
			TOTAL	\$440.00

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- Credit card payment is being made online (if electronically filed), or is attached hereto (if paper filed), in the amount of
- The Director is hereby authorized to charge any additional fees which may be required for the papers being filed herewith and for which no payment is enclosed herewith, or credit any overpayment to Deposit Account No. 15-0030.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030.

Submitted by:

Gregory J. Maier

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